Probe Card Sizes

(The sizes differ depending on the specifications applied. For the details, contact TEL.)

Outline: Max. 350 mm Diameter

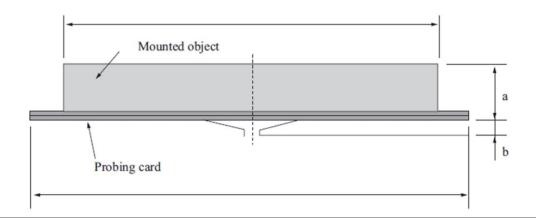
Thickness: a.Object height

Max. 40 mm (distance from the bottom face of the board)

b.Needle probe height

Max. 20 mm (distance from the bottom face of the board)

Weight: Max. 4 kg



Main Unit Dimensions

Overall dimensions: (Units: mm) 1090 (W) × 1065 (D) × 930 (H)

(Excluding the height of signal tower and LCD panel)

Weight: (Units: kg) Approximately 785 (standard specifications)

Utilities

Power: voltage AC 100 - 120 V (-15% - +10%)

AC 200 - 240V (-10% - +10%)

current (prober capacity) AC 100 - 120 V 30 A

AC 200 - 240 V 15 A

power frequency 50/60 Hz

momentary interruption retention time 50 ms

power consumption Max. 1.5 kVA (with the optional

Hot Chuck and motor type Test Head Transfer Mechanism.)

Dry air: pressure Max. 0.4 MPa 39.2N (4 kgf/cm²) - 0.7 MPa

flow rate 18 1/min (standard) 48 1/min (2nd loader specifications)

connections 1/4 inch fitting (uses outer shape φ6/inner diameter φ4 tubes)

Vacuum: pressure Max. -50 kPa (-400 mmHg)

flow rate 15 1/min

connections 1/4 inch fitting (uses outer shape \$\phi6/\text{inner diameter \$\phi4\$ tubes)

Environmental Conditions

Ambient Temperature: 25°C ±3°C Humidity: Max. 65%

Vibration: Frequency of vibration on the floor after installation of prober...The

recommended value is 10 Hz or more.

Probing Unit Specifications

Positioning accuracy guarantee range: $X/Y = \pm 4 \mu m$ $Z = \pm 3 \mu m$ Contact accuracy guarantee when using ASU: $X/Y = \pm 4 \mu m$ $Z = \pm 5 \mu m$

Card holder attachment parallelism:

(Standard: chuck surface)

25 μm/Max. φ200

XY Stage

XY probing area: From Insert Ring Center

X: ±118 mm Y: +230 mm -110 mm

Drive method: AC servo motor

Lead of ball screw: 4 mm

Accuracy: ±2 µm

Control resolution: 0.4 µm

Maximum speed: 0.2 m/s

Z Stage

Z Stroke: 77 mm Contact point setting area: 75.3 mm

Drive method: 5 phase stepping motor

Direct Coupling

Lead of ball screw: 2 mm

Accuracy: Within ±2 μm Maximum speed: 0.04 m/s

Overshoot: Within 4 µm (when raised at 500µm)

Control resolution: 2μm Withstand load: 40 kg

According as change the acceleration, correspond max. 60 kg

Z stage rigidity (When a chuck temperature is nomal):

Loading R90mm position

Horizontal rigidity 6.6 μm/98N (6.6 μm/10 kgf)
Vertical rigidity 11.9 μm/98N (11.9 μm/10 kgf)

Loading center

Vertical rigidity 8.4 µm/98N (8.4 µm/10 kgf)

Wafer Specifications

Sizes: 4, 5, 6 and 8 inches

Thickness: 150 - 1000 µm (Discuss separately in case of 350 µm or lower)

Die Size: 350 - 76000 μm (die size for parameter input: 300 μm or greater,

die size that can be aligned: 350 µm or greater)

Number of Dies: Up to 200 dies (in X-axis direction) × 200 dies (in Y-axis direction)

When control map is used, up to 250 dies (in X-axis direction) ×

250 dies (in Y-axis direction)

(Discuss separately in any other case)

Warp: Discuss separately

Weight: Max. 110 g

Infrared Rays Transmissivity: Less than 4% in the whole range between 860 nm and 900 nm

Cassette Specifications

Size: Conforms to SEMI standards

Materials: Plastics/Aluminum

Note: Ask about cassettes which do not conform to SEMI standards.

Use plastic cassettes which have electric prevention treatment.

Indexer Unit

Maximum speed: Max. 100 mm/s

Drive method: 5 phase stepping motor

Pulley & belt ratio 1:1

Lead of ball screw: 4mm

Accuracy: ±10 μm

Control resolution: 8 µm

Wafer sensing method: LED transmissive method

Display Unit

LCD Panel: 10.4 inch color display

640 × 480 dots

Japanese/English/Alphanumeric

Touch panel

Built-in Hard Disk

FDD: 3.5 inch 1.4 MB 1 unit

HDD: 2.5 inch 2MB 1 unit

Theta Mechanism

Theta rotation mechanism: ±7.5° when probing

+14.5° when transferring wafer

Drive method: 5 phase stepping motor

Direct coupling

Lead of ball screw: 1 mm

Accuracy: Within ±0.5µm

Control resolution: 0.00022° 0.5 µm (8 inch top)

Chuck Top

Flatness: 15 μm (Ordinary temperature ≤ t ≤ 100°C)

 $30 \mu m (100 < t \le 150 ^{\circ}C)$

Alignment

Wafer alignment: Pattern matching method (individual check is required in case of

a special wafer pattern)

Card alignment: Pattern matching method or needle point detection method

(individual check is required in case of a special card)

Inker Drive

Inker drive circuits: Equipped with 4 circuits

5 Autoloader Unit Specifications

Cassette: Items conforming SEMI standards
Cassette setting: 1 loader (2nd optional loader possible)

Method of handling: Wafer back side vacuum mechanical arm transfer

Wafers in cassette can be randomly accessed.

Tweezers Unit

Tweezers Arm

Maximum stroke: 302 mm Maximum speed: 355 mm/s

Drive method: 5 phase stepping motor

Pulley & belt ratio 1:1

Accuracy: ±17 μm Control resolution: 50.8 μm

Tweezers Rotation Unit

Rotation time: 1s/90°

Drive method: 5 phase stepping motor

Pulley & belt ratio 1:7.2

Accuracy: ±15 μm

Control Resolution: 0.005° (±353 µm on the chuck top)

Prealignment Unit

Rotation speed: 1s/360°

Drive method: 5 phase stepping motor

Direct drive

Prealignment method: LED transmissive method

Accuracy: X, Y ±300 μm

Control resolution: theta ±0.17° (±314 µm on the chuck top)